ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

METHOD OF CONFLICT AVOIDANCE IN FABRICATION OF GATE-SHRINK ALTERNATING PHASE SHIFTING MASKS

Application Number:

Confirmation Number:

First Named Applicant:

Lars Liebmann

Attorney Docket Number:

FIS920030379

Art Unit:

Examiner:

Search string:

(6277527 or 6523165 or 6541165 or 6569583 or 6584610 or 6593038 or 6622288

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US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
N	1	6277527	2001-08-21	O'Grady et al.			
170	2	6523165	2003-02-18	Liu et al.			
TX.	3	6541165	2003-04-01	Pierrat			
X	4	6569583	2003-05-27	Cho et al.			
- TX 2	5	6584610	2003-06-24	Wu et al.		_	
N	6	6593038	2003-07-15	Cho et al.			f
	7	6622288	2003-09-16	Wang et al.			

Signature

Examiner Name	, Date
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ŽR.	Вј	*Alternating Phase Shi	fted Mask for Logi	c Gate	Levels, Design and N	lask Ma	nufac	turing", L	ars Liebm electronics	ann, Ioai , 12 page	
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DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant applicant. ibmf100417000ids2

EXAMINER

SUPPLEMENTAL INFORMATION DISCLOSURE

Sheet _ 1 _ of _ 1 _

FORM PFO 1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO.: FIS920030379US1	SERIAL NO.: 10/708,055	
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CONCERT 1 NOTES	e several sheets if necessary)	FILING DATE: February 5, 2004	GROUP: 1756	

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

REFERENCE DESIGNATION			U.S. PATEN				
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FOREIGN PATENT DOCUMENTS

		PUBLICATION	COUNTRY OR		SUB-	TRANSI	ATION		
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OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

"Alternating Phase Shifted Mask for Logic Gate Levels, Design and Mask Manufacturing", Lars Liebmann, Ioana Graur, William Leipold, James Oberschmidt, David O'Grady, Denis Regaill; IBM Microelectronics, East Fishkill, New York and Burlington, Vermont. SPIE Conference on Optical Microlithography XII, March 1999, Vol. 3679, Pages 27-37.

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